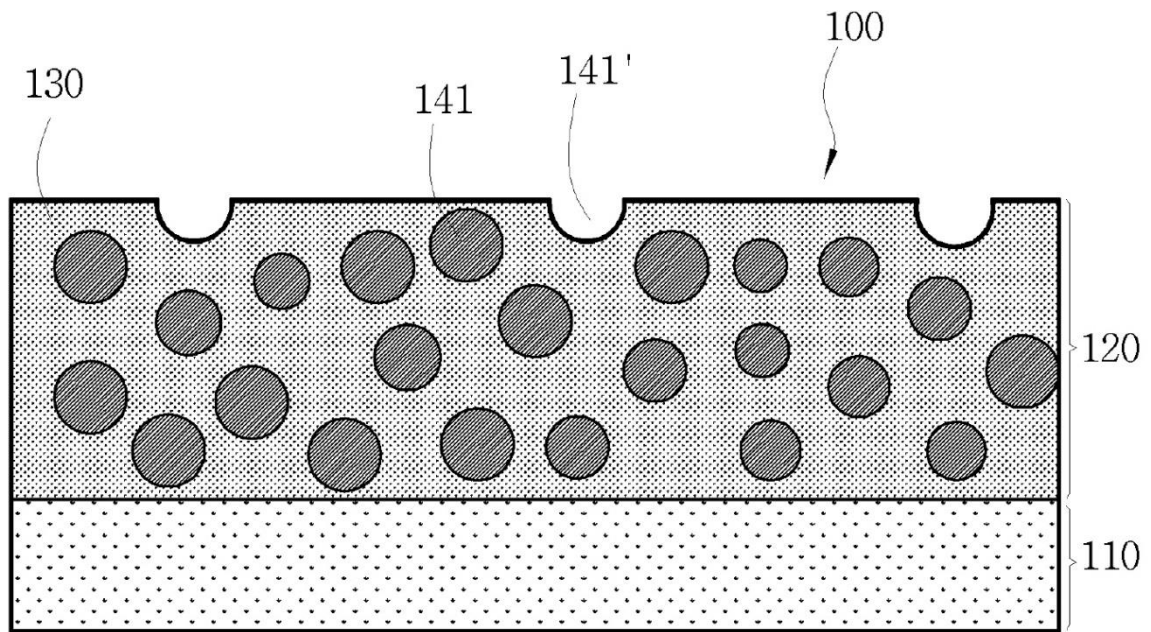
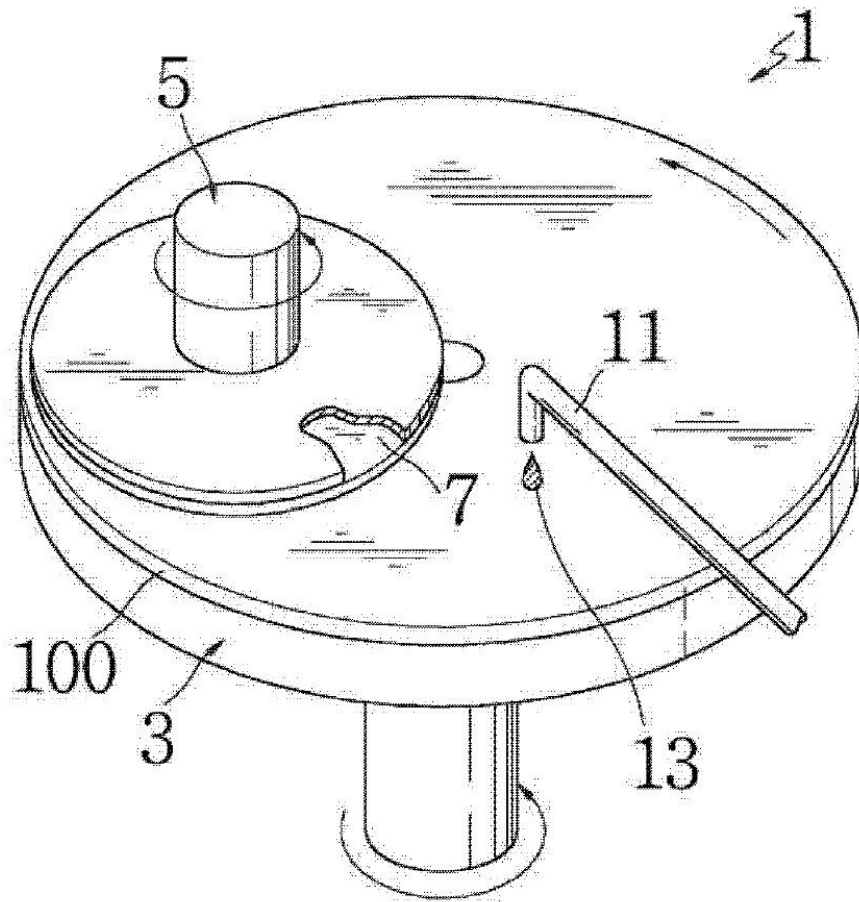


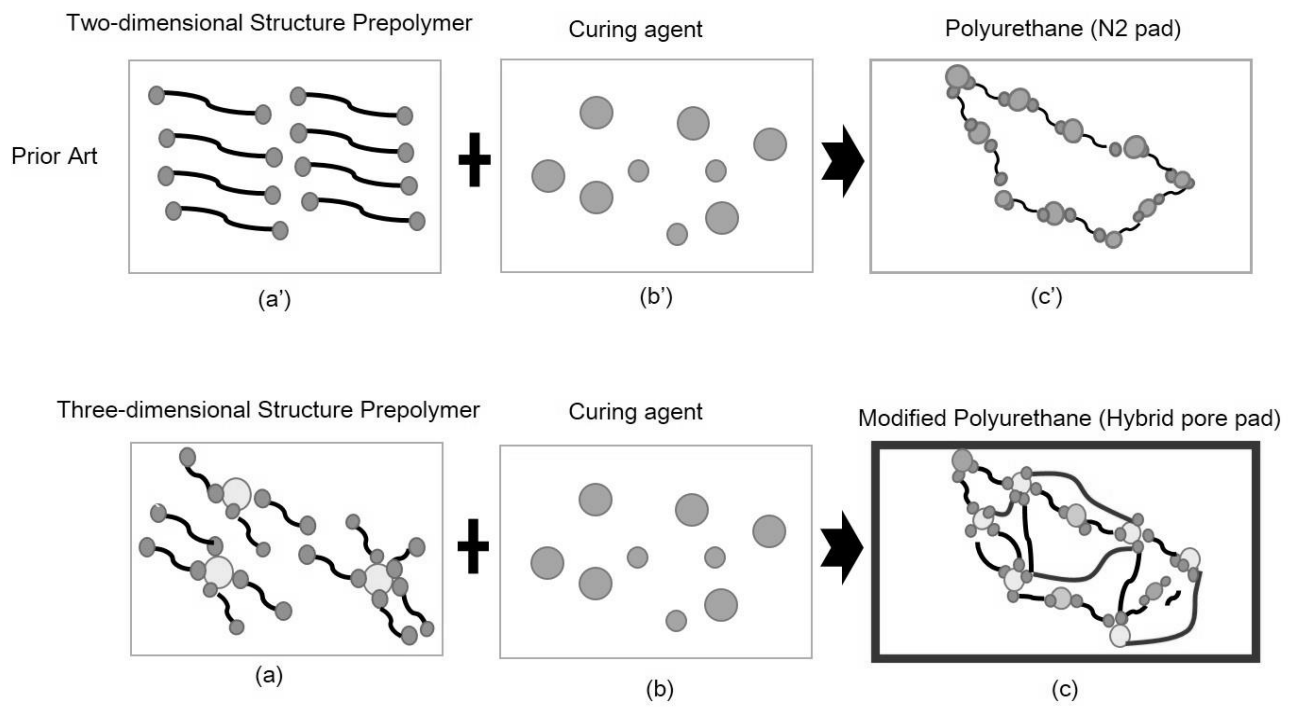
【Fig. 1】



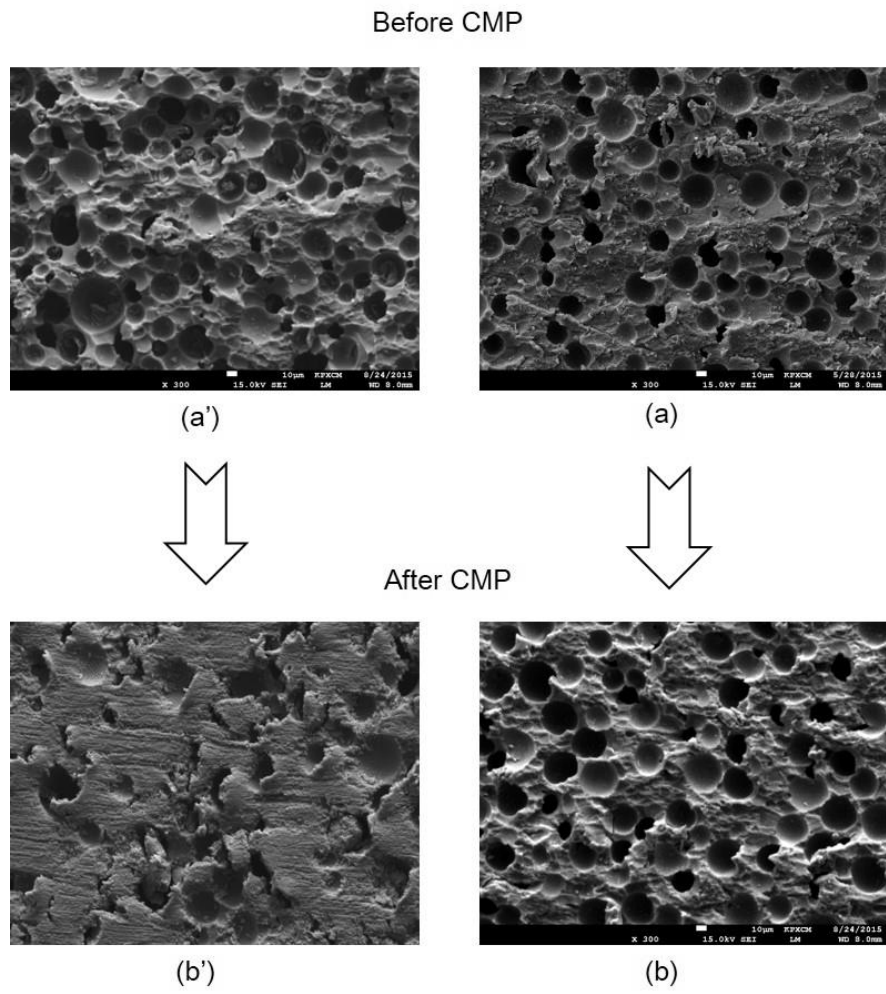
【Fig. 2】



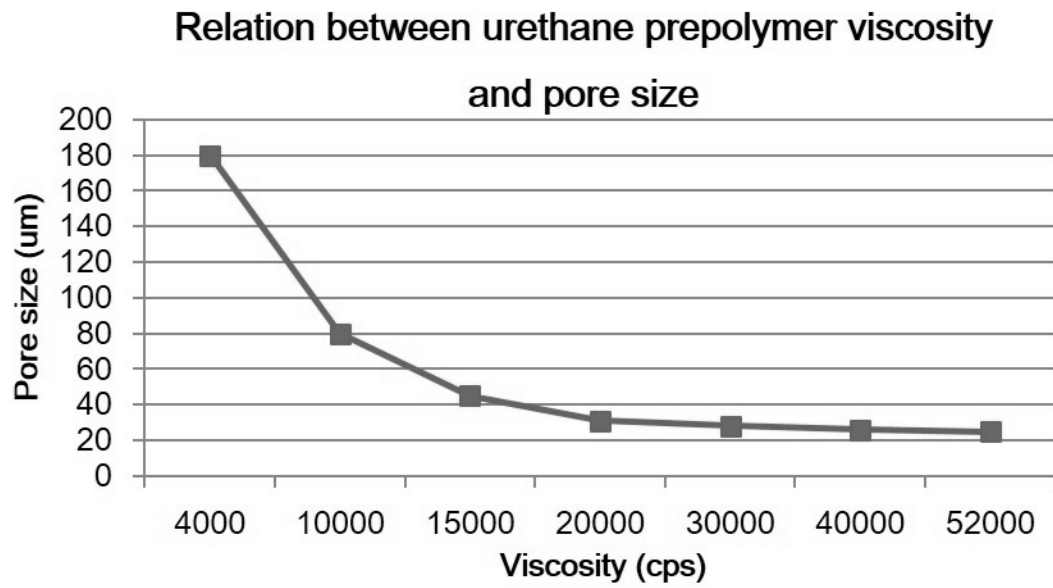
【Fig. 3】



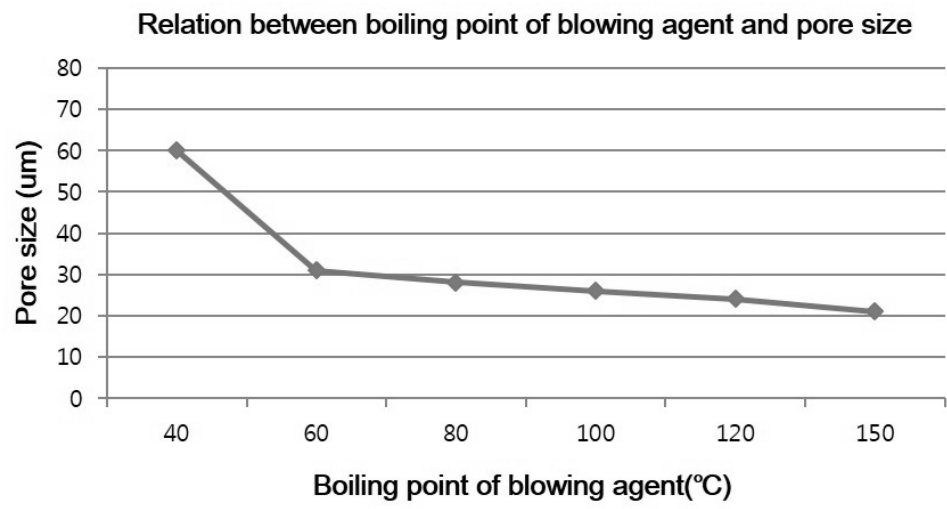
【Fig. 4】



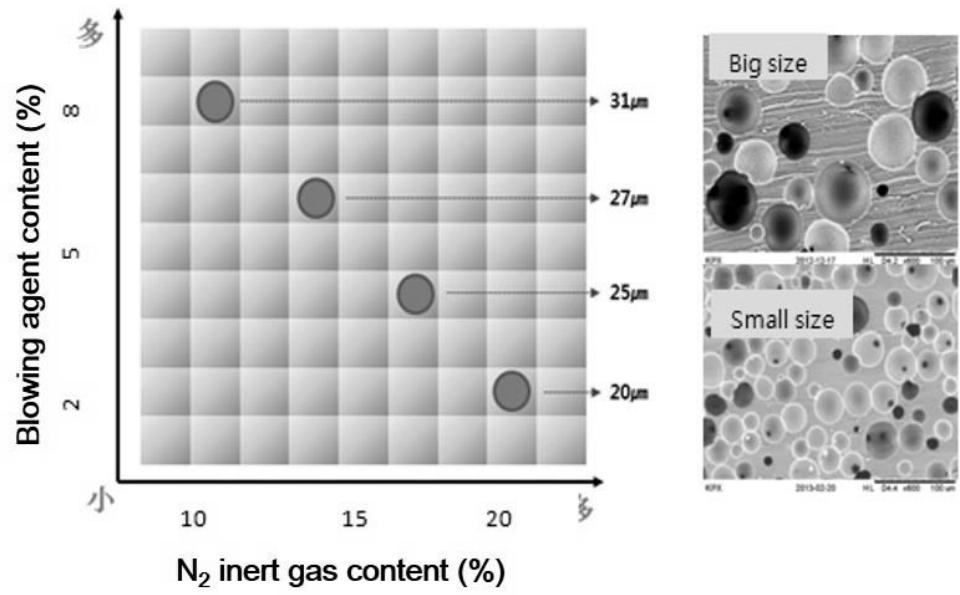
【Fig. 5】



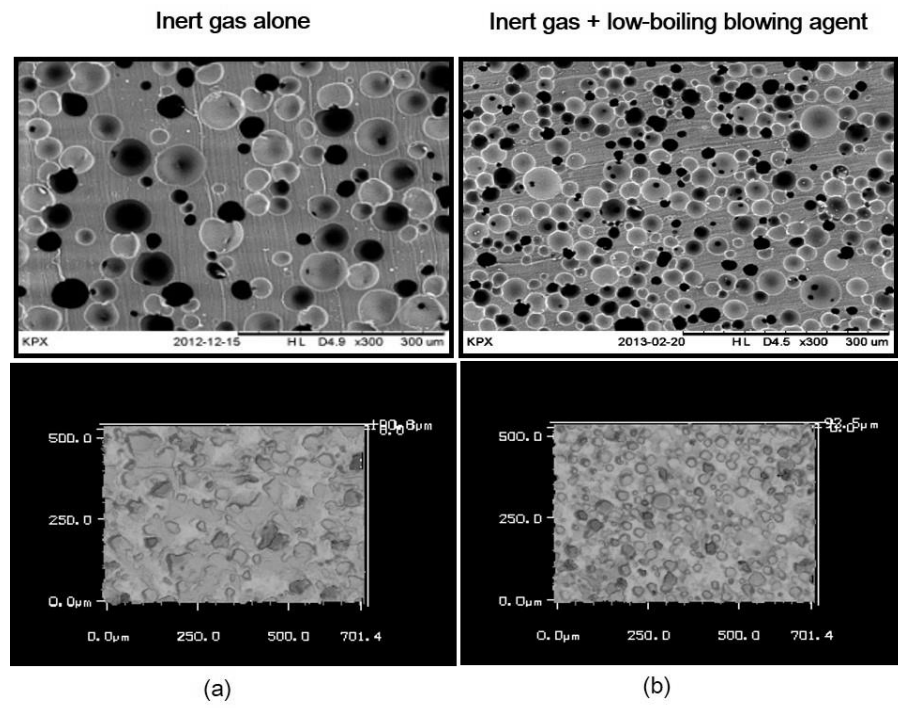
【Fig. 6】



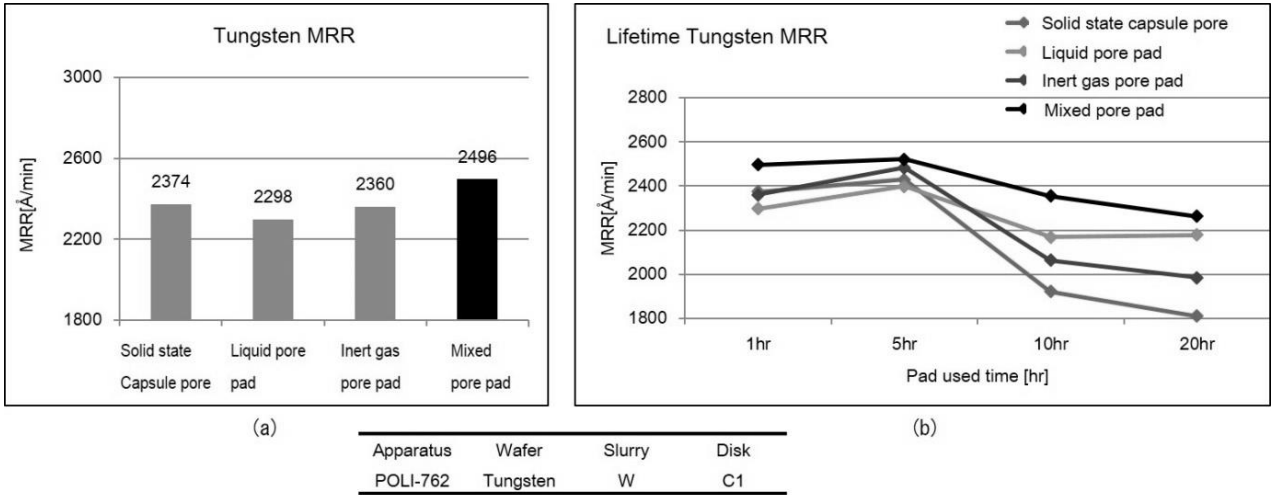
【Fig. 7】



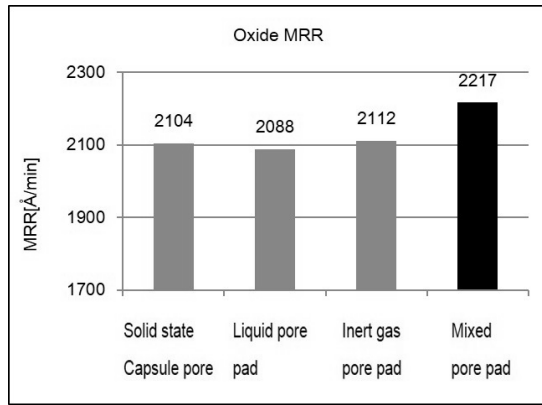
【Fig. 8】



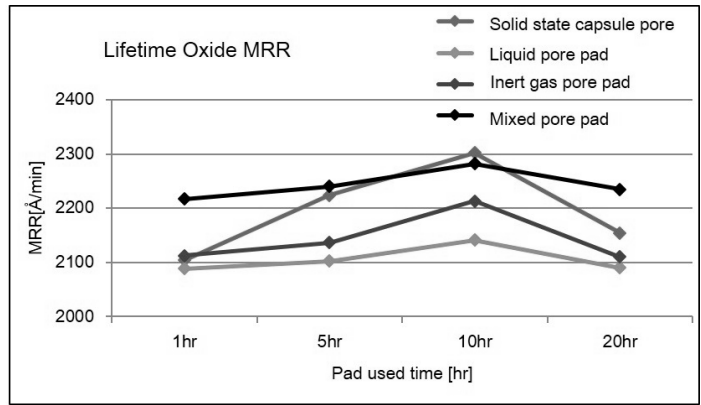
【Fig. 9】



【Fig. 10】



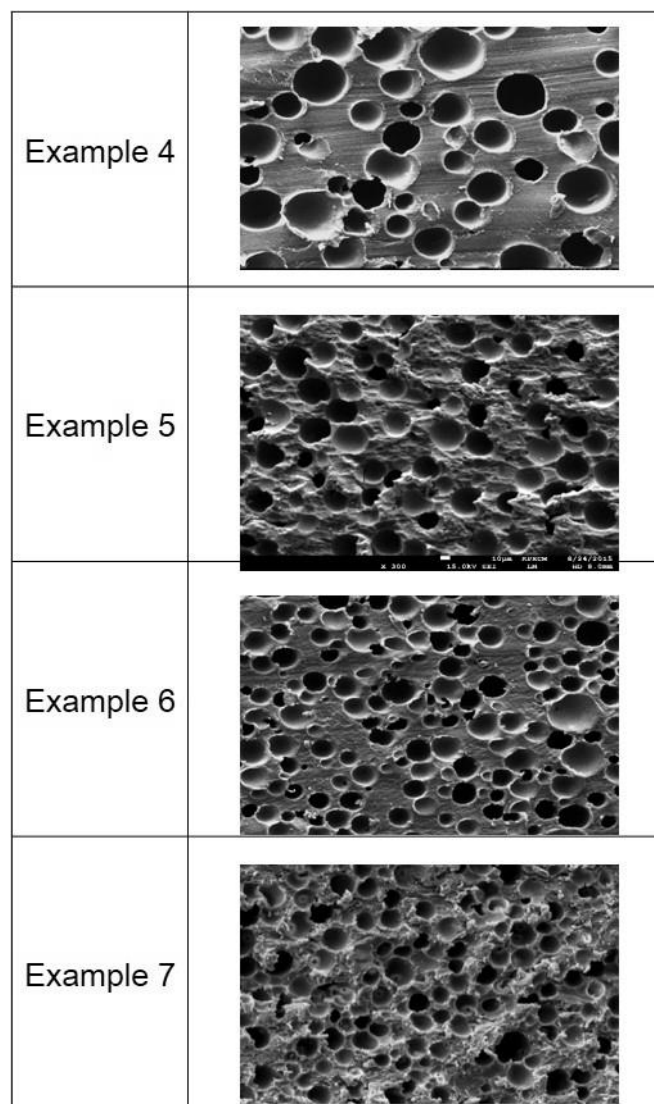
(a)



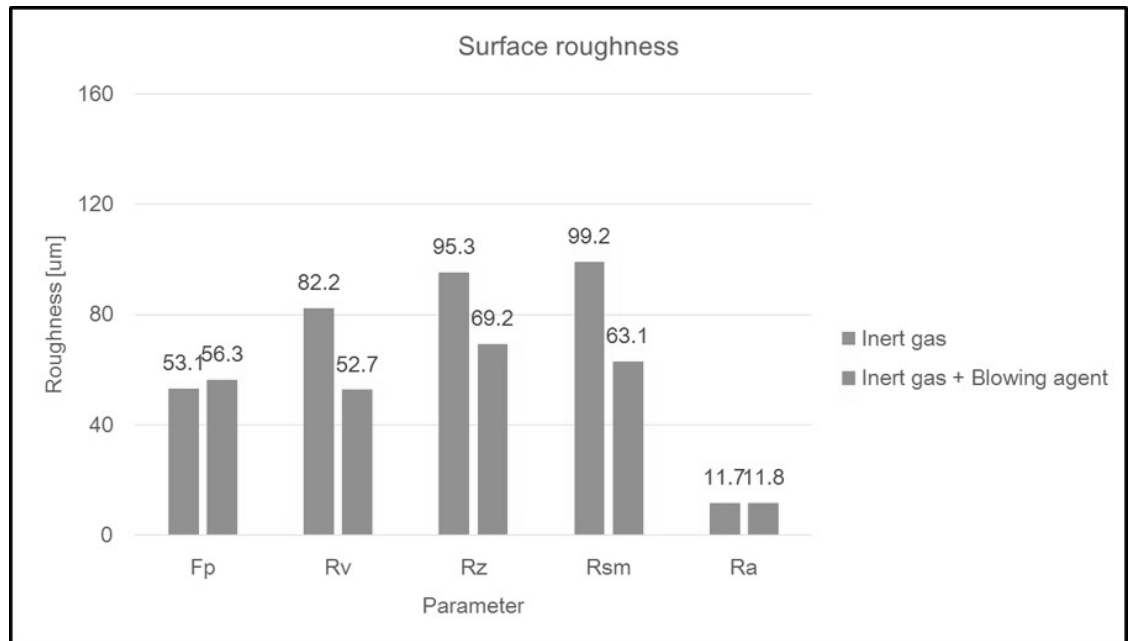
(b)

Apparatus	Wafer	Slurry	Disk
POLI-762	Oxide	T	C7

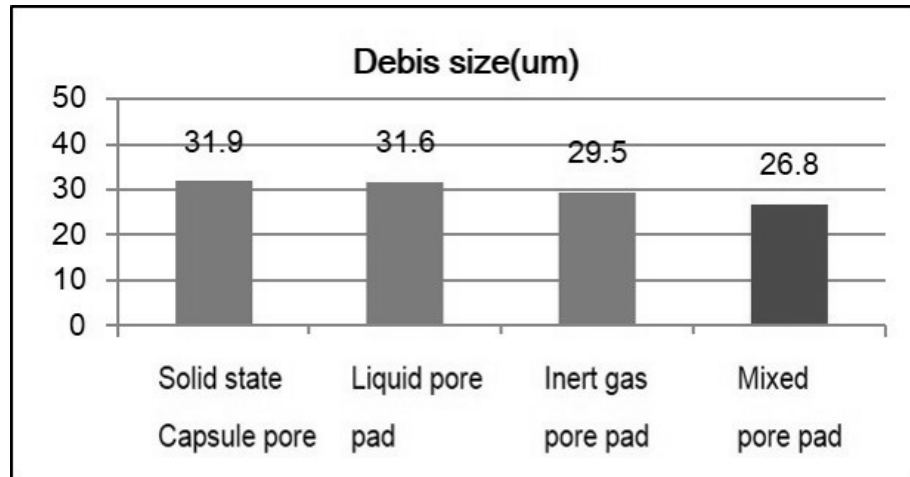
【Fig. 11】



【Fig. 12a】



【Fig. 12b】



【Fig. 12c】

